Code: 20EC2501A

## III B.Tech - I Semester – Regular / Supplementary Examinations NOVEMBER 2023

## **SENSOR TECHNOLOGY**

(Common to ALL Branches)

Duration: 3 hours Max. Marks: 70

Note: 1. This paper contains questions from 5 units of Syllabus. Each unit carries 14 marks and have an internal choice of Questions.

2. All parts of Question must be answered in one place.

BL – Blooms Level CO – Course Outcome

The state of the s				BL	СО	Max. Marks
generalized measurement system and explain the function of various elements with suitable measurement system.  b) Discuss various types of sensors with respect to specifications, sensor material and applications.  OR  2 a) Elaborate on Static characteristics of measurement system with necessary graphs.  b) In detail describe commonly used various  L2 CO1 7 M  7 M  7 M  7 M  7 M		•	UNIT-I		•	-
respect to specifications, sensor material and applications.  OR  2 a) Elaborate on Static characteristics of measurement system with necessary graphs.  b) In detail describe commonly used various  L2 CO1 7 M  The spect to specifications, sensor material and L2 CO1 7 M  The spect to specifications, sensor material and L2 CO1 7 M  The spect to specifications, sensor material and L2 CO1 7 M  The spect to specifications, sensor material and L2 CO1 7 M  The spect to specifications, sensor material and L2 CO1 7 M  The specifications are specifications, sensor material and L2 CO1 7 M  The specifications are specifications, sensor material and L2 CO1 7 M  The specifications are specifications.	1	a)	generalized measurement system and explain the function of various elements	L2	CO1	7 M
2 a) Elaborate on Static characteristics of measurement system with necessary graphs.  b) In detail describe commonly used various  L2 CO1 7 M		b)	respect to specifications, sensor material and	L2	CO1	7 M
measurement system with necessary graphs.  L2 CO1 7 M  In detail describe commonly used various  L2 CO1 7 M			OR			
1 2 CO1 7 M	2	a)		L2	CO1	7 M
		b)	_	L2	CO1	7 M

		UNIT-II			
3	a)	Describe the significance of dielectric constant and explain in detail Capacitance water level sensor with necessary graphs.		CO2	7 M
	b)	Write short notes on specific resistivity, strain sensitivity and moisture sensitivity.	L2	CO2	7 M
	•	OR			
4	a)	Analyze piezoelectric effect with necessary formulation for voltage generated.	L4	CO2	7 M
	b)	Design the dynamic models of sensor elements characterized by zero-order and first-order.	L3	CO2	7 M
		UNIT-III			
5	a)	Explain instrumentation amplifier with circuit diagram and obtain the expression for gain.		CO3	7 M
	b)	With necessary diagram discuss the importance of charge – balance V/F converter.	L2	CO3	7 M
		OR			
6	a)	The four arms of a Wheatstone bridge are arranged as follows: AB is a inductive sensor; BC is a non-reactive resistor R=1000 $\Omega$ ; CD is R=833 $\Omega$ in series with C=0.38 $\mu F$ ; DA is R=16,800 $\Omega$ . If the supply frequency is 50 Hz, determine the inductance of AB inductive sensor at balance condition.	L3	CO3	7 M

b)	Write short notes on batteries for low power sensors.	L2	CO3	7 M			
			<u> </u>				
	UNIT-IV						
a)	Describe with neat diagram microwave						
	occupancy detector for measuring Doppler	L2	CO4	7 M			
	frequency.						
b)	Calculate displacement produced in a spring						
		L3	CO4	7 M			
	Spring co-efficient k=10 <sup>-3</sup> m/N.						
	OR						
a)	Analyze accelerometer with its model.	L4	CO4	7 M			
b)	Analyze the functioning of optical	Ι /	COA	7 M			
	gyroscope.	L4	CO4	/ IVI			
	UNIT-V						
a)	With neat diagram analyze sputtering						
	process in a vacuum chamber for surface	L4	CO5	7 M			
	processing.						
b)	Enumerate different types of sensor	1.2	COS	7 M			
	materials.	LZ		/ IVI			
OR							
a)	Discuss the role of silicon as a sensing	1.2	COS	7 M			
	material in sensor fabrication.	L2		7 M			
b)	Discuss photolithography techniques.	L2	CO5	7 M			
	a) a) b) a) b)	UNIT-IV  a) Describe with neat diagram microwave occupancy detector for measuring Doppler frequency.  b) Calculate displacement produced in a spring force sensor when applied force = 4N, Spring co-efficient k=10 <sup>-3</sup> m/N.  OR  a) Analyze accelerometer with its model.  b) Analyze the functioning of optical gyroscope.  UNIT-V  a) With neat diagram analyze sputtering process in a vacuum chamber for surface processing.  b) Enumerate different types of sensor materials.  OR  a) Discuss the role of silicon as a sensing material in sensor fabrication.	UNIT-IV  a) Describe with neat diagram microwave occupancy detector for measuring Doppler frequency.  b) Calculate displacement produced in a spring force sensor when applied force = 4N, L3 Spring co-efficient k=10 <sup>-3</sup> m/N.  OR  a) Analyze accelerometer with its model. L4  b) Analyze the functioning of optical gyroscope.  UNIT-V  a) With neat diagram analyze sputtering process in a vacuum chamber for surface processing.  b) Enumerate different types of sensor materials.  OR  a) Discuss the role of silicon as a sensing material in sensor fabrication.	UNIT-IV  a) Describe with neat diagram microwave occupancy detector for measuring Doppler frequency.  b) Calculate displacement produced in a spring force sensor when applied force = 4N, L3 CO4 Spring co-efficient k=10 <sup>-3</sup> m/N.  OR  a) Analyze accelerometer with its model.  b) Analyze the functioning of optical gyroscope.  UNIT-V  a) With neat diagram analyze sputtering process in a vacuum chamber for surface processing.  b) Enumerate different types of sensor materials.  OR  a) Discuss the role of silicon as a sensing material in sensor fabrication.			